



10013802-1

Response

In re Patent Application of:

Inventor:

Chen, et al

Confirmation No:

1660

Serial No.

10/085,866

Examiner:

Hu, Shouxiang

Filed:

Feb 27, 2002

Group Art Unit:

2811

Title:

Emission Layer Formed By Rapid Thermal Formation Process

Commissioner for Patents P O BOX 1450 Alexandria VA 22313-1450

RESPONSE TO RESTRICTION REQUIREMENT

In response to your Office Action/Restriction Requirement dated July 15, 2003; Applicants affirm the election of **Group II**, (Claims 13-19) without traverse.

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Respectfully submitted,

Chen, et al

Timothy F. Myers,

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Attorney For Applicants

I hereby certify that this correspondence is being deposited on the date indicated below with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, PQ-Box 1450, Alexandria, VA 22313.

Signature

Typed Name

Date of Signatur

10013802

PATENT

<u>IN</u>	THE UNITED STATES PATENT A	ND TRADEMARK OFFIC	E 1 1 per Andt -
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Serial No.:	10/085866))	
Filing Date:	Feb 27 2002)	TEC
For:	EMISSION LAYER FORMED BY RAPID THERMAL FORMATION PROCESS)))	RECEIVED APR-4 2002 APR-4 2002 TECHNOLOGY CENTER 2800
Art Unit:	Unassigned)	ED 2002 ENTER
PRELIMINARY AMENDMENT 8			

Assistant Commissioner for Patents Washington, D.C. 20231

Dear Sir:

Prior to consideration and calculating the fees for the above-referenced Application, please amend the Application as follows:

In the Specification:

Please replace the paragraph beginning on page 3, line $\frac{30}{20}$, with the following rewritten paragraph:

Referring now to FIG. 1, a preferred embodiment emitter 10 of the invention is shown in a two-dimensional schematic cross section. The preferred embodiment emitter 10 is a metal-insulator-semiconductor (MIS) device including a flat